

FORM PTO-1449		Docket Number (Optional) 005586/D-8326		Parent Application Number 08/912,505		
INFORMATION DISCLOSURE CITATION IN AN APPLICATION		Applicant Hidenori Ogata et al.				
(Use several sheets if necessary)		Parent Filing Date August 14, 1997		Parent Group Art Unit 2822		
U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
MW	5,432,122	7/1995	Chae			
MW	5,496,768	3/1996	Kudo			
MW	4,234,358	11/1980	Celler et al.			
MW	5,365,875	11/1994	Asai et al.			
MW	5,683,935	11/1997	Miyamoto et al.			
MW	5,529,951	6/1996	Noguchi et al.			
MW	5,591,668	6/1997	Maegawa et al.			
MW	4,514,895	5/1985	Nishimura			
MW	5,815,494	9/1998	Yamazaki et al.			
MW	5,767,003	6/1998	Noguchi			
MW	5,454,347	10/1995	Shibata et al.			
MW	5,533,040	7/1996	Zhang			
FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION (YES/NO)
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
MW	M. Kamiya et al., "Eximer Laser Annealing SLA3600," pp. 24-25 with its English translations and Document 1 (Electronic Display Forum '96 program cover sheet, April 17-19, 1996) and Document 2 (List of presentations at Forum '96, including "Eximer Laser Annealing System SLA 3600, April 19, No. 18) showing the laid open date of 4/17-4/19/1996					
MW	Mamoru Furuta et al., "Bottom-Gate Poly-Si Thin Film Transistors Using XeCl Excimer Laser Annealing and Ion Doping Techniques," <i>IEEE Transactions on Electron Devices</i> , vol. 40, No. 11, November, 1993					
EXAMINER MWileczewski		DATE CONSIDERED 6/02				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.						

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 09/29/98
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